

SDS-AirOxDUO

POU AIR OXIDATION

Air oxidation solution for high-volume semiconductor manufacturing



Applications

- > Semiconductor processes

Features

- > Primary 140 liter cartridge x2
- > Standard Air oxidation function
- > Pressure monitoring

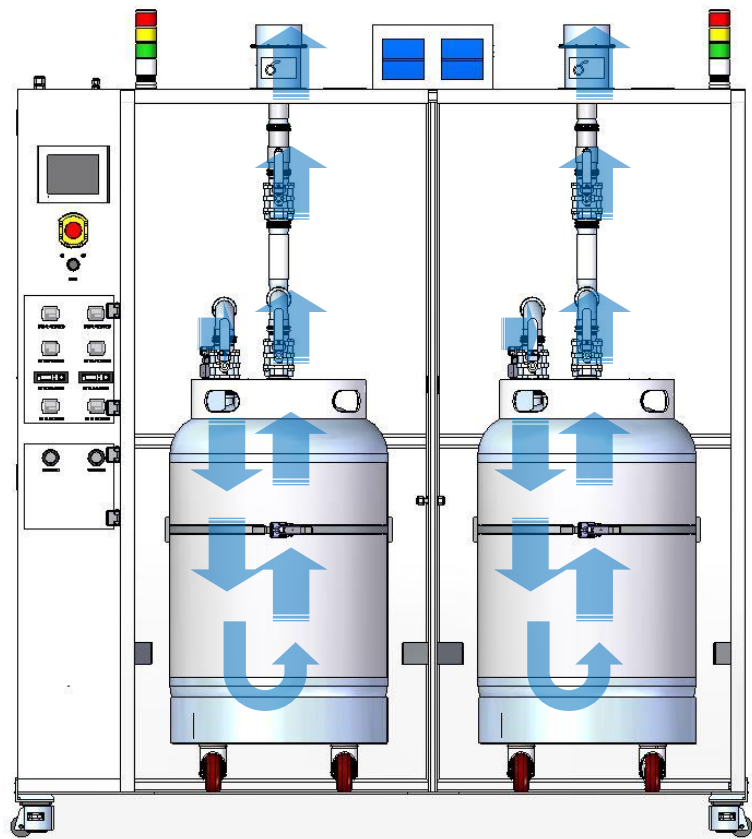
Option


- > Temperature monitoring and display
- > N2 ejector
- > Gas monitoring options
- > CDA MFC

Benefits

- > High Oxidation efficiency
- > Low overall CoO

System Specifications



 Air Oxidation Operation

- MTBF: >8,300 hours
- MTTR: <3 hour
- MTPP: <3 hour

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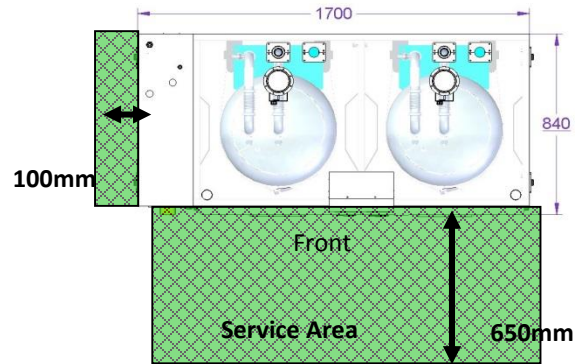
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Dimensions and Weight

SDS-1000DUO

Dimension 1700 x 840 x 1650
(W x D x H in mm)

Weight 520
(kg)



Utilities

Item	Type	Typical Usage	Connection Type
Electricity	208VAC1 Phase	<1 KW	5A
N2	3 ~ 6 kg/cm ²	60~100 LPM(DUO)	1/2" SS compression
Air(CDA)	5 ~ 6.5 kg/cm ²	30~120 LPM(DUO)	3/8" SS compression (Oxidation)
Gas Exhaust	-50 ~ -100 mmH2O	0.2 m ³ /min	KF40 Flange (2 Port)
Cabinet Exhaust	-50 ~ -60 mmH2O	1.5 m ³ /min	Ø100mm

Environment

- Temperature: 5 ~ 30 °C
- Relative Humidity: < 65%